## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Cyril Cabral, Jr., et al.

Examiner:

Long Pham

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For: REDUCTION OF SILICIDE FORMATION TEMPERATURE ON

SiGe CONTAINING SUBSTRATES

Confirmation No: 1278

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## RESPONSE UNDER 37 C.F.R. § 1.116

Sir:

In response to the Office Action dated October 24, 2006, applicants submit the following amendments and remarks for entry into the record of the above-identified patent application.

## CERTIFICATION OF ELECTRONIC TRANSMISSION

I hereby certify that this document is being filed in the United States Patent and Trademark Office on the date shown below via electronic transmission.

Dated: December 21, 2006

Leslie S. Szivos, Ph.D.